



PATENT
Customer No. 22,852
Attorney Docket No. 04329.2566

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

SHINICHI ITO et al. ✓

Application No.: 09/842,403 ✓

Filed: April 26, 2001 ✓

For: FILM FORMATION METHOD, SEMICONDUCTOR
ELEMENT AND METHOD THEREOF, AND
METHOD OF MANUFACTURING A DISK-
SHAPED STORAGE MEDIUM

#7
Electron
1. main
9/30/02
Group Art Unit: 2823
Examiner: M. Estrada

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Commissioner for Patents and Trademarks
Washington, DC 20231

Sir:

RESPONSE TO RESTRICTION REQUIREMENT

In a restriction requirement dated August 28, 2002, the Examiner required
restriction under 35 U.S.C. § 121 between:

Group I - Claims 1-18, 20, 22, and 23, and ✓

Group II - Claims 19 and 21.

Applicants provisionally elect to prosecute Group I, claims 1-18, 20, 22, and 23,
drawn to a method of making a semiconductor device, without traverse.

Please grant any extensions of time required to enter this response and charge
any additional required fees to our Deposit Account No. 06-0916.

Respectfully submitted,

FINNEGAN, HENDERSON, FARABOW,
GARRETT & DUNNER, L.L.P.

By: *Walt* *Joe* *Reg. No. 45,137*

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Dated: Sept 27, 2002

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